

## **IN THE CLAIMS:**

This listing of claims will replace all prior versions, and listings, of claims in the application.

1. (Previously Presented) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition from a below toward an anode or a cathode facing downward under a pressure lower than atmosphere pressure; and

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the anode or the cathode.

2. (Previously Presented) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition from a below toward an anode or a cathode facing downward under a pressure of  $1 \times 10^2$  to  $1 \times 10^5$  Pa; and

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the anode or the cathode.

3. (Previously Presented) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition from a below toward an anode or a cathode facing downward under a pressure lower than atmosphere pressure; and

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode or the cathode and volatilizing a

solvent in the solution in a duration before the solution arrives at the anode or the cathode.

4. (Withdrawn) A fabrication method of a light-emitting device comprising the steps of:  
ejecting a solution containing a light-emitting body composition from the below toward an anode or a cathode under a pressure lower than atmosphere pressure;  
commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the anode or the cathode by previously heating the anode or the cathode; and  
forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode or the cathode.

5. (Withdrawn) A fabrication method of a light-emitting device comprising the steps of:  
ejecting a solution containing a light-emitting body composition from the below toward an anode or a cathode under a pressure lower than atmosphere pressure;  
commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the anode or the cathode by previously heating the anode or the cathode at from room temperature to 200 °C; and  
forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode or the cathode.

6. (Previously Presented) A fabrication method of a light-emitting device comprising the steps of:  
setting up an anode or a cathode facing downward in a range of 0° to 30° relative to a horizontal plane;

ejecting a solution containing a light-emitting body composition from a below under a pressure lower than atmosphere pressure; and

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the anode or the cathode.

7. (Previously Presented) A fabrication method of a light-emitting device comprising the steps of:

setting up an anode or a cathode facing downward in a range of  $0^{\circ}$  to  $30^{\circ}$  relative to a horizontal plane;

ejecting a solution containing a light-emitting body composition from a below under a pressure lower than atmosphere pressure; and

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode or the cathode and volatilizing a solvent in the solution in a duration before the solution arrives at the substrate.

8. (Withdrawn) A fabrication method of a light-emitting device comprising the steps of:

setting up an anode or a cathode in a range of  $0^{\circ}$  to  $30^{\circ}$  relative to a horizontal plane;

ejecting a solution containing a light-emitting body composition from the below under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the anode or the cathode by previously heating the anode or the cathode; and

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode or the cathode.

9. (Withdrawn) A fabrication method of a light-emitting device comprising the steps of:  
setting up an anode or a cathode in a range of  $0^{\circ}$  to  $30^{\circ}$  relative to a horizontal plane;  
ejecting a solution containing a light-emitting body composition from the below under a pressure lower than atmosphere pressure;  
commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the anode or the cathode by previously heating the anode or the cathode at from room temperature to  $200^{\circ}\text{C}$ ; and  
forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode or the cathode.

10. (Previously Presented) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition toward an anode provided on a substrate facing downward under a pressure lower than atmosphere pressure;

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the anode; and

forming a cathode on the light-emitting body by a sputter method or an evaporation method after forming the film of the light-emitting body composition,

wherein the fabrication method of the light-emitting device is further characterized in that the formation of the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of  $0^{\circ}$  to  $30^{\circ}$  relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the

the substrate surface.

11. (Previously Presented) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition toward an anode facing downward under a pressure lower than atmosphere pressure;

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the anode and volatilizing a solvent in the solution in a duration before the solution arrives at the substrate; and

forming a cathode on the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the formation of the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of  $0^{\circ}$  to  $30^{\circ}$  relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

12. (Withdrawn - Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition toward an anode under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the anode or the cathode by previously heating the anode;

forming a thin film having at least one layer structuring a light-emitting body by depositing a

remaining of the light-emitting body composition on the anode; and

forming a cathode ~~[[on]]~~ over the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the formation of the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

13. (Withdrawn - Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition toward an anode under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the anode or the cathode by previously heating the anode at from room temperature to 200 °C;

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode; and

forming a cathode ~~[[on]]~~ over the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the formation of the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

14. (Previously Presented) A fabrication method of a light-emitting device according to claims 10 or 11,

wherein each of the formations of the thin film having at least one layer structuring the light-emitting body and the cathode is performed in a deposition apparatus in a multi-chamber scheme without a release to the air.

15. (Previously Presented) A fabrication method of a light-emitting device according to claims 10 or 11,

wherein each of the formations of the thin film having at least one layer structuring the light-emitting body and the cathode is performed in a deposition apparatus in an in-line scheme without a release to the air.

16. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition toward a cathode provided on a substrate facing downward under a pressure lower than atmosphere pressure;  
forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the cathode; and

forming an anode over the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the formation of a thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from

from the below of the substrate surface.

17. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition toward a cathode facing downward under a pressure lower than atmosphere pressure;

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the cathode and volatilizing a solvent in the solution in a duration before the solution arrives at the substrate; and

forming an anode ~~[[on]]~~ over the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the formation of the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

18. (Withdrawn - Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition toward a cathode under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the cathode by previously heating the cathode;

forming a thin film having at least one layer structuring a light-emitting body by depositing a



remaining of the light-emitting body composition on the cathode; and

forming an anode ~~[[on]]~~ over the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the formation of at the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

19. (Withdrawn - Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition toward a cathode under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the cathode by previously heating the cathode at from room temperature to 200 °C;

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the cathode; and

forming an anode ~~[[on]]~~ over the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the formation of the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

20. (Previously Presented) A fabrication method of a light-emitting device according to claims 16 or 17,

wherein each of the formations of the thin film having at least one layer structuring the light-emitting body and the cathode is performed in a deposition apparatus in a multi-chamber scheme without a release to the air.

21. (Previously Presented) A fabrication method of a light-emitting device according to claims 16 or 17,

wherein each of the formations of the thin film having at least one layer structuring the light-emitting body and the cathode is performed in a deposition apparatus in an in-line scheme without a release to the air.

22. (Previously Presented) A fabrication method of a light-emitting device according to any one of claims 1, 3, 6-7, 10-11, 16-17,

wherein under the pressure lower than atmosphere pressure is in an inert gas atmosphere at  $1 \times 10^3$  to  $1 \times 10^5$  Pa.

23. (Previously Presented) A fabrication method of a light-emitting device according to any one of claims 1, 3, 6-7, 10-11, 16-17,

wherein under the pressure lower than atmosphere pressure is in an inert gas atmosphere at  $1 \times 10^2$  to  $1 \times 10^5$  Pa.

24-29. (Canceled)

30. (New) A fabrication method of a light-emitting device according to any one of claims 1, 3, 6-7, 10-11, 16-17, further comprising:

forming a hole transporting layer in a HTL deposition chamber of a multi chamber;

forming an electron transport layer in an ETL deposition chamber of the multi chamber;

wherein the light emitting body is interposed between the hole transporting layer and the electron transport layer and is formed in a light-emitting layer deposition chamber of the multi chamber,

wherein the HTL deposition chamber and the ETL deposition chamber each includes heads of solution-applying device.